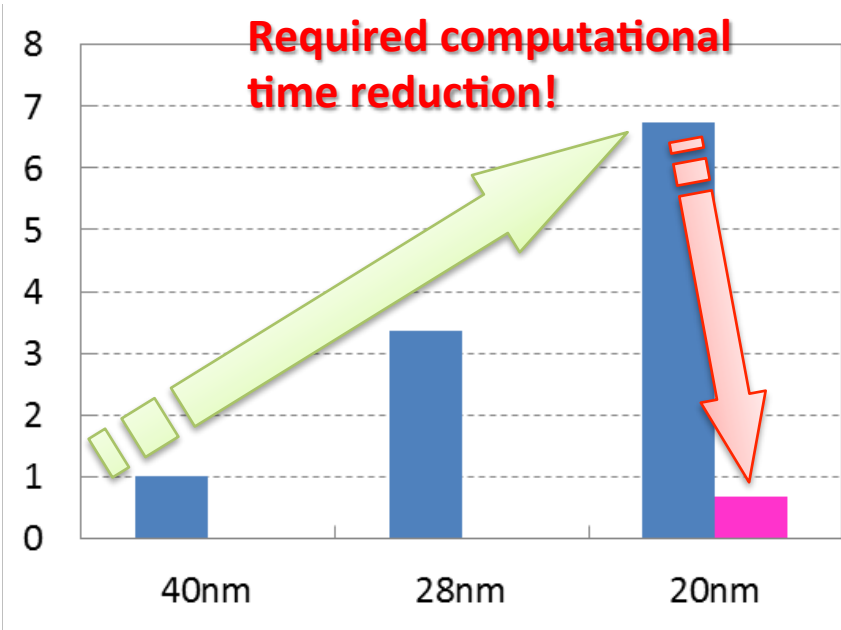


Ratio of lithography simulation time
(normalized by 40nm node)



Technology node